

Computer-Aided Design for Micro-Electro-Mechanical Systems Eigenvalues, Energy Losses, and Dick Tracy Watches

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Sandia, 26 Jan 2006

The Computational Science Picture

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- Application modeling
 - Checkerboard resonator
 - Disk resonator
 - Shear ring resonator
- Mathematical analysis
 - Physical modeling and finite element technology
 - Structured eigenproblems and reduced-order models
 - Parameter-dependent eigenproblems
- Software engineering
 - HiQLab
 - SUGAR
 - FEAPMEX

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Outline

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- 1 Resonant MEMS
- 2 Anchor Losses
- 3 Complex Symmetry
- 4 Disk Resonator Analysis

Outline

CAD for
MEMS

Resonant
MEMS

MEMS Basics

RF MEMS

Checkerboard Model

HiQLab

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- 1 Resonant MEMS
- 2 Anchor Losses
- 3 Complex Symmetry
- 4 Disk Resonator Analysis

What are MEMS?

CAD for
MEMS

Resonant
MEMS

MEMS Basics

RF MEMS

Checkerboard Model

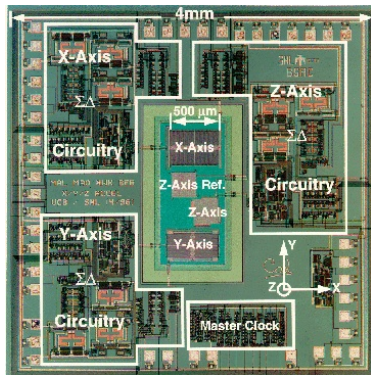
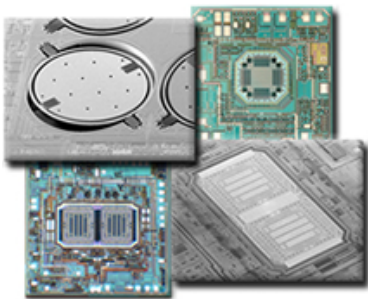
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Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



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CAD for
MEMS

Resonant
MEMS

MEMS Basics

RF MEMS

Checkerboard Model

HiQLab

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



MEMS Basics

CAD for
MEMS

Resonant
MEMS
MEMS Basics
RF MEMS
Checkerboard Model
HiQLab

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- Micro-Electro-Mechanical Systems
 - Chemical, fluid, thermal, optical (MECFTOMS?)
- Applications:
 - Sensors (inertial, chemical, pressure)
 - Ink jet printers, biolab chips
 - Radio devices: cell phones, inventory tags, pico radio
- Use integrated circuit (IC) fabrication technology
- Tiny, but still classical physics

Radio-Frequency MEMS

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Resonant
MEMS

MEMS Basics

RF MEMS

Checkerboard Model

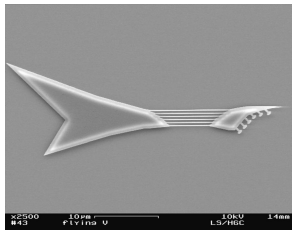
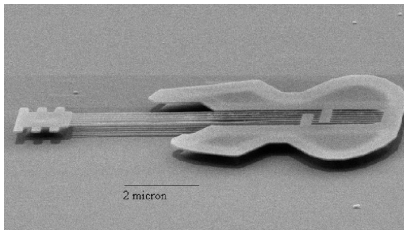
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Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



Microguitars from Cornell University (1997 and 2003)

- MHz-GHz mechanical resonators
- Impact: smaller, lower-power cell phones
- Other uses:
 - Sensing elements (e.g. chemical sensors)
 - Really high-pitch guitars

Micromechanical Filters

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Resonant
MEMS

MEMS Basics

RF MEMS

Checkerboard Model

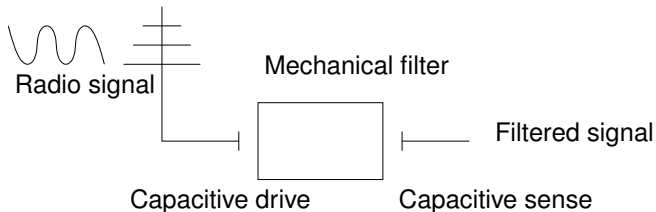
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Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



- Mechanical high-frequency (high MHz-GHz) filter
 - Your cell phone is mechanical!
 - New MEMS filters can be integrated with circuitry
 - ⇒ smaller and lower power

Ultimate Success

CAD for
MEMS

Resonant
MEMS

MEMS Basics

RF MEMS

Checkerboard Model

HiQLab

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

“Calling Dick Tracy!”



Designing Transfer Functions

CAD for
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Resonant
MEMS

MEMS Basics

RF MEMS

Checkerboard Model

HiQLab

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

Time domain:

$$\begin{aligned}Mu'' + Cu' + Ku &= b\phi(t) \\ y(t) &= p^T u\end{aligned}$$

Frequency domain:

$$\begin{aligned}-\omega^2 M\hat{u} + i\omega C\hat{u} + K\hat{u} &= b\hat{\phi}(\omega) \\ \hat{y}(\omega) &= p^T \hat{u}\end{aligned}$$

Transfer function:

$$\begin{aligned}H(\omega) &= p^T (-\omega^2 M + i\omega C + K)^{-1} b \\ \hat{y}(\omega) &= H(\omega) \hat{\phi}(\omega)\end{aligned}$$

Narrowband Filter Needs

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MEMS

MEMS Basics

RF MEMS

Checkerboard Model

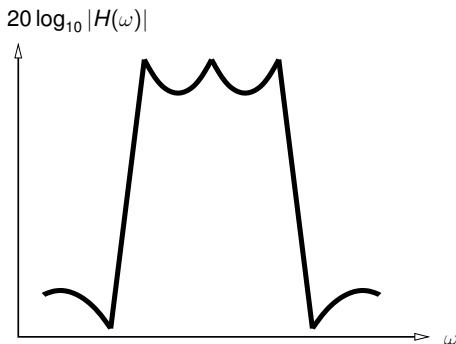
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Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



- Want “sharp” poles for narrowband filters
- $\implies$ Want to minimize damping

Checkerboard Resonator

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Resonant
MEMS

MEMS Basics

RF MEMS

Checkerboard Model

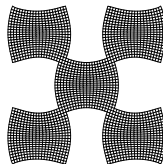
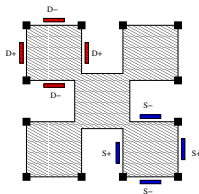
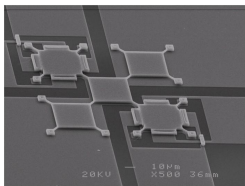
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Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



- Anchored at outside corners
- Excited at **northwest** corner
- Sensed at **southeast** corner
- Surfaces move only a few nanometers

Checkerboard Model Reduction

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Resonant
MEMS

MEMS Basics

RF MEMS

Checkerboard Model

HiQLab

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- Finite element model: $N = 2154$
 - Expensive to solve for every $H(\omega)$ evaluation!
- Build a **reduced-order model** to approximate behavior
 - Reduced system of 80 to 100 vectors
 - Evaluate $H(\omega)$ in milliseconds instead of seconds
 - Without damping: standard Arnoldi projection
 - With damping: Second-Order ARnoldi (SOAR)

Checkerboard Simulation

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RF MEMS

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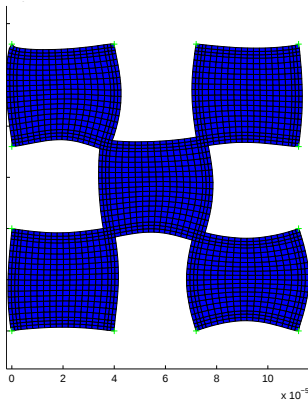
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Anchor
Losses

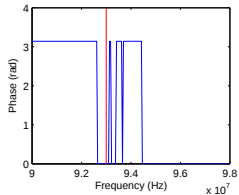
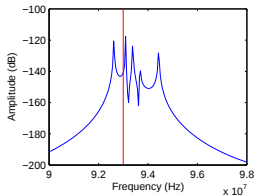
Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



93



Checkerboard Measurement

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Resonant
MEMS

MEMS Basics

RF MEMS

Checkerboard Model

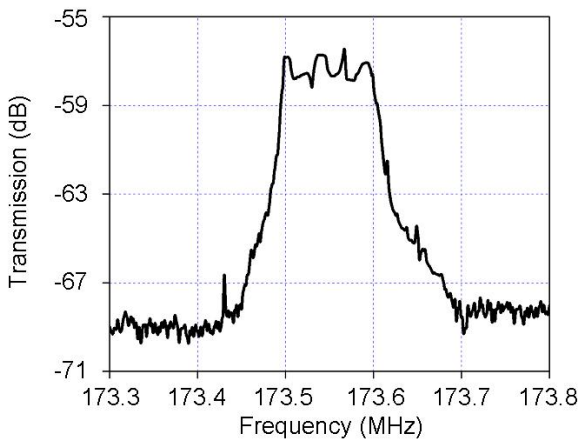
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Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



S. Bhawe, MEMS 05

Damping and Q

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Resonant
MEMS

MEMS Basics

RF MEMS

Checkerboard Model

HiQLab

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

Designers want high *quality of resonance* (Q)

- Dimensionless damping in a one-dof system

$$\frac{d^2 u}{dt^2} + Q^{-1} \frac{du}{dt} + u = F(t)$$

- For a resonant mode with frequency $\omega \in \mathbb{C}$:

$$Q := \frac{|\omega|}{2 \operatorname{Im}(\omega)} = \frac{\text{Stored energy}}{\text{Energy loss per radian}}$$

Enter HiQLab

CAD for
MEMS

Resonant
MEMS

MEMS Basics

RF MEMS

Checkerboard Model

HiQLab

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- Existing codes do not compute quality factors
- ... and awkward to prototype new solvers
- ... and awkward to programmatically define meshes
- So I wrote a new finite element code: HiQLab

HiQLab Structure

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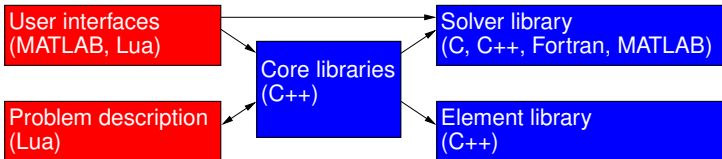
Resonant
MEMS
MEMS Basics
RF MEMS
Checkerboard Model
HiQLab

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



- Full scripting language for mesh input
- Callbacks for boundary conditions, material properties
- MATLAB interface for quick algorithm prototyping
- Cross-language bindings are automatically generated

Contributions

CAD for
MEMS

Resonant
MEMS

MEMS Basics

RF MEMS

Checkerboard Model

HiQLab

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- Built predictive model used to design checkerboard
- Used model reduction to get thousand-fold speedup – fast enough for interactive use
- Wrote FEAPMEX to script parameter studies
- Wrote a new code, HiQLab, to study damping

Outline

CAD for
MEMS

Resonant
MEMS

**Anchor
Losses**

Substrate modeling

1-D Example

Finite Elements

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- 1 Resonant MEMS
- 2 Anchor Losses**
- 3 Complex Symmetry
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Example: Disk Resonator

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Substrate modeling

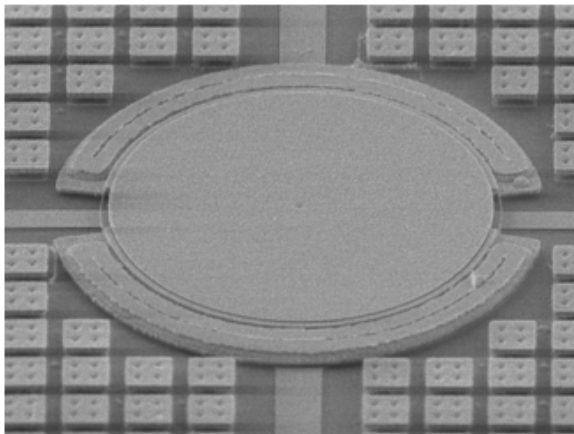
1-D Example

Finite Elements

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



SiGe disk resonators built by E. Quévy

Damping Mechanisms

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Substrate modeling

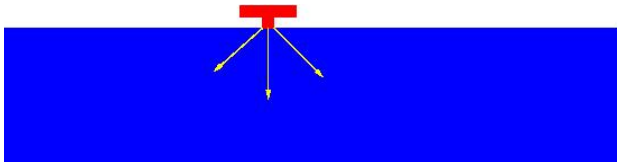
1-D Example

Finite Elements

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



Possible loss mechanisms:

- Fluid damping
- Material losses
- Thermoelastic damping
- **Anchor loss**

Model substrate as semi-infinite with a

Perfectly Matched Layer (PML).

Perfectly Matched Layers

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Substrate modeling

1-D Example

Finite Elements

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- Complex coordinate transformation
- Generates a “perfectly matched” absorbing layer
- Idea works with general linear wave equations
 - Electromagnetics (Bereng r, 1994)
 - Quantum mechanics – *exterior complex scaling* (Simon, 1979)
 - Elasticity in standard finite element framework (Basu and Chopra, 2003)

Model Problem

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Substrate modeling

1-D Example

Finite Elements

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- Domain: $x \in [0, \infty)$
- Governing eq:

$$\frac{\partial^2 u}{\partial x^2} - \frac{1}{c^2} \frac{\partial^2 u}{\partial t^2} = 0$$

- Fourier transform:

$$\frac{d^2 \hat{u}}{dx^2} + k^2 \hat{u} = 0$$

- Solution:

$$\hat{u} = c_{\text{out}} e^{-ikx} + c_{\text{in}} e^{ikx}$$

Model with Perfectly Matched Layer

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Substrate modeling

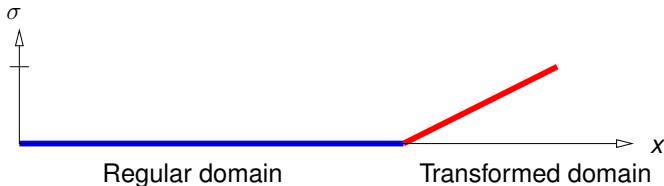
1-D Example

Finite Elements

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



$$\frac{d\tilde{x}}{dx} = \lambda(x) \text{ where } \lambda(s) = 1 - i\sigma(s)$$

$$\frac{d^2 \hat{u}}{d\tilde{x}^2} + k^2 \hat{u} = 0$$

$$\hat{u} = c_{\text{out}} e^{-ik\tilde{x}} + c_{\text{in}} e^{ik\tilde{x}}$$

Model with Perfectly Matched Layer

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Substrate modeling

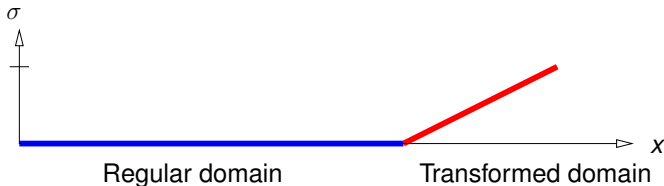
1-D Example

Finite Elements

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



$$\frac{d\tilde{x}}{dx} = \lambda(x) \text{ where } \lambda(s) = 1 - i\sigma(s),$$

$$\frac{1}{\lambda} \frac{d}{dx} \left(\frac{1}{\lambda} \frac{d\hat{u}}{dx} \right) + k^2 \hat{u} = 0$$

$$\hat{u} = c_{\text{out}} e^{-ikx - k\Sigma(x)} + c_{\text{in}} e^{ikx + k\Sigma(x)}$$

$$\Sigma(x) = \int_0^x \sigma(s) ds$$

Model with Perfectly Matched Layer

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Substrate modeling

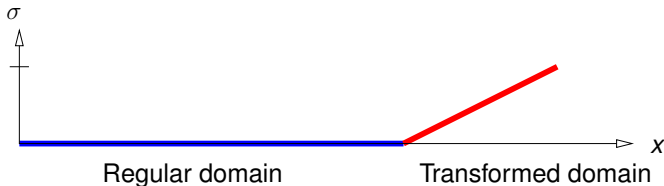
1-D Example

Finite Elements

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



If solution clamped at $x = L$ then

$$\frac{c_{\text{in}}}{c_{\text{out}}} = O(e^{-k\gamma}) \text{ where } \gamma = \Sigma(L) = \int_0^L \sigma(s) ds$$

Model Problem Illustrated

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Substrate modeling

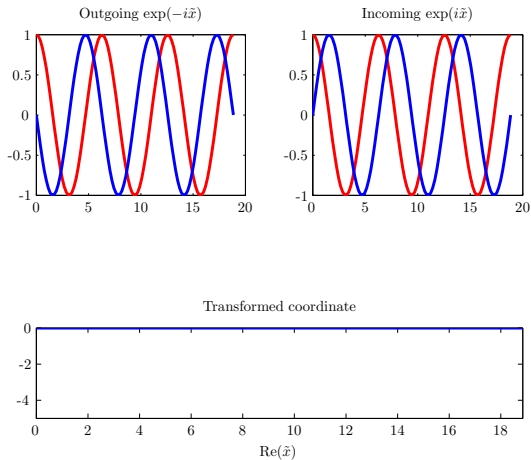
1-D Example

Finite Elements

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



Model Problem Illustrated

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Substrate modeling

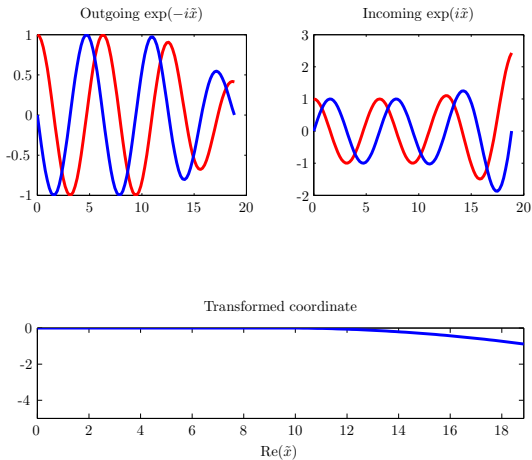
1-D Example

Finite Elements

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



Model Problem Illustrated

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Substrate modeling

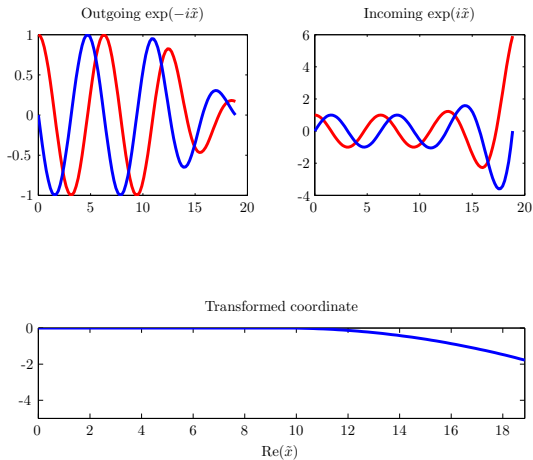
1-D Example

Finite Elements

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



Model Problem Illustrated

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Substrate modeling

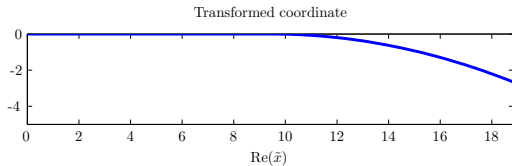
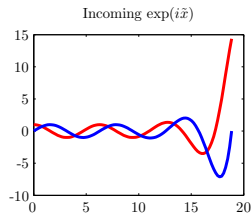
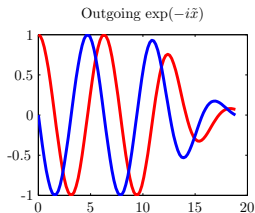
1-D Example

Finite Elements

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



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CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Substrate modeling

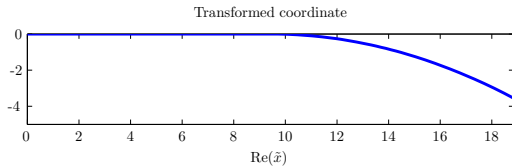
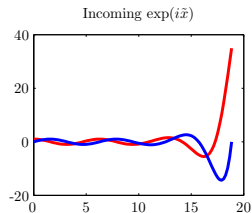
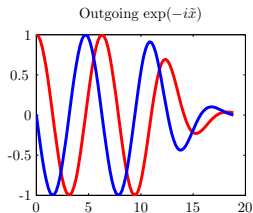
1-D Example

Finite Elements

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



Model Problem Illustrated

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Substrate modeling

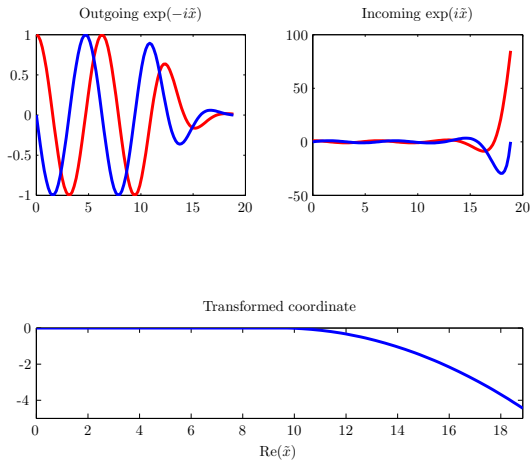
1-D Example

Finite Elements

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



Finite Element Implementation

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Substrate modeling

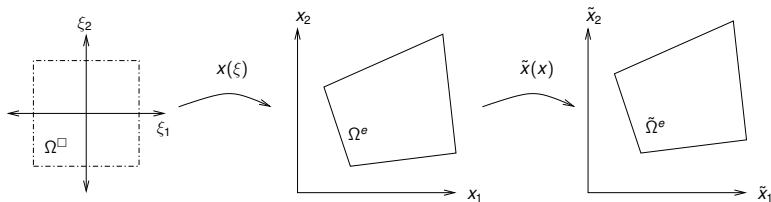
1-D Example

Finite Elements

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



- Combine PML and isoparametric mappings

$$\mathbf{k}^e = \int_{\Omega^\square} \tilde{\mathbf{B}}^T \mathbf{D} \tilde{\mathbf{B}} \tilde{J} d\Omega^\square$$

$$\mathbf{m}^e = \int_{\Omega^\square} \rho \mathbf{N}^T \mathbf{N} \tilde{J} d\Omega^\square$$

- Matrices are *complex symmetric*

Outline

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- 1 Resonant MEMS
- 2 Anchor Losses
- 3 Complex Symmetry**
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Eigenvalues and Model Reduction

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

Want to know about the transfer function $H(\omega)$:

$$H(\omega) = p^T (K - \omega^2 M)^{-1} b$$

Can either

- Locate poles of H (eigenvalues of (K, M))
- Plot H in a frequency range (Bode plot)

Usual tactic: subspace projection

- Build an Arnoldi basis V
- Compute with much smaller $V^* K V$ and $V^* M V$

Can we do better?

Variational Principles

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MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- Variational form for complex symmetric eigenproblems:
 - Hermitian (Rayleigh quotient):

$$\rho(v) = \frac{v^* K v}{v^* M v}$$

- Complex symmetric (modified Rayleigh quotient):

$$\theta(v) = \frac{v^T K v}{v^T M v}$$

- First-order accurate eigenvectors $\implies$
Second-order accurate eigenvalues.
- Key: relation between left and right eigenvectors.

Accurate Model Reduction

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- Build new projection basis from V :

$$W = \text{orth}[\text{Re}(V), \text{Im}(V)]$$

- $\text{span}(W)$ contains both $\mathcal{K}_n$ and $\bar{\mathcal{K}}_n$
 $\implies$ double digits correct vs. projection with V
- W is a real-valued basis
 $\implies$ projected system is complex symmetric

Contributions

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- New formulation of perfectly matched layers
 - Easy to apply PML to axisymmetric, 2D, or 3D models
 - Same formulation applies to electromagnetics, etc.
- Analysis of discretization error for perfectly matched layers
 - Results in cheap, automatic parameter optimization
- Structure-preserving model reduction for complex symmetric systems
 - Double accuracy for same work as standard method

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CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- 1 Resonant MEMS
- 2 Anchor Losses
- 3 Complex Symmetry
- 4 Disk Resonator Analysis**

Disk Resonator Simulations

CAD for
MEMS

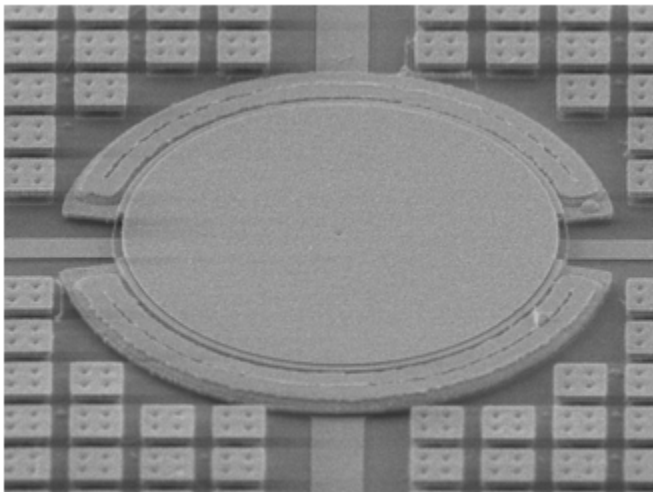
Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



Disk Resonator Mesh

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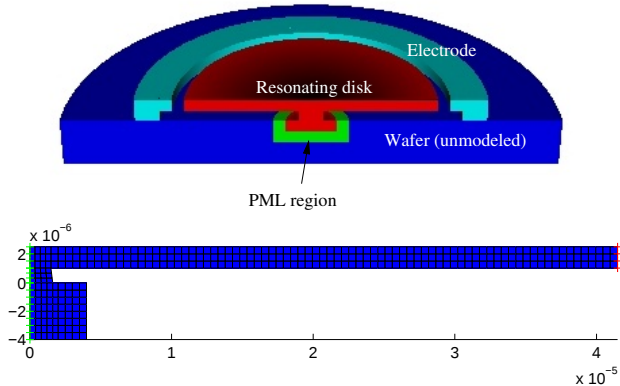
Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



- Axisymmetric model with bicubic mesh
- About 10K nodal points in converged calculation

Mesh Convergence

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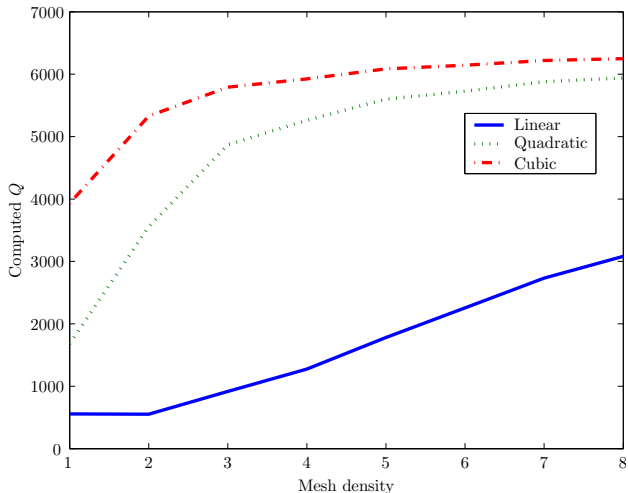
Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



Cubic elements converge with reasonable mesh density

Model Reduction Accuracy

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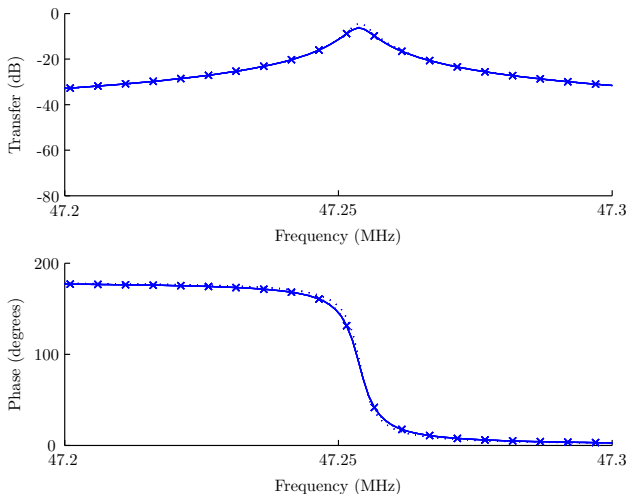
Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



Results from ROM (solid and dotted lines) near indistinguishable from full model (crosses)

Model Reduction Accuracy

CAD for
MEMS

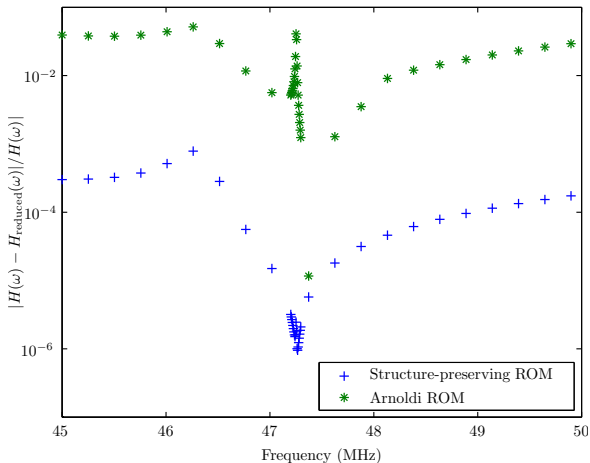
Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



Preserve structure $\implies$
get twice the correct digits

Response of the Disk Resonator

CAD for
MEMS

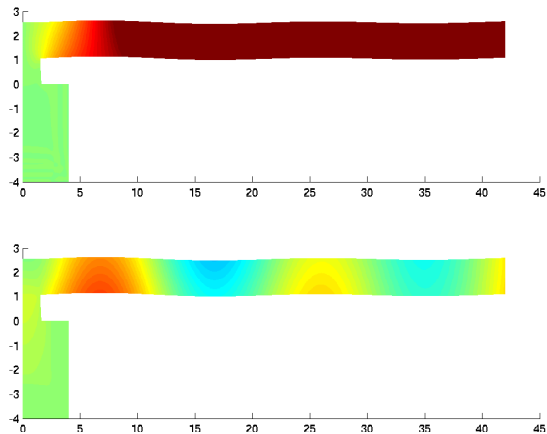
Resonant
MEMS

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Symmetry

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Conclusions



Time-Averaged Energy Flux

CAD for
MEMS

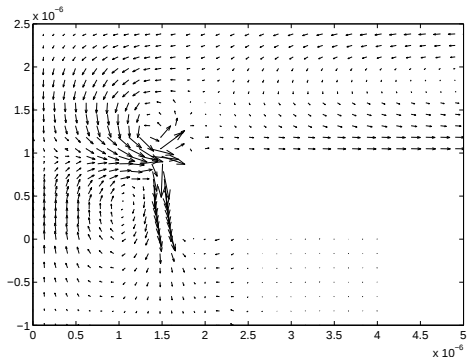
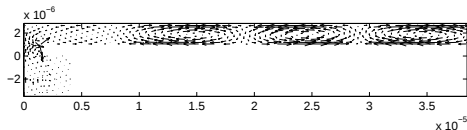
Resonant
MEMS

Anchor
Losses

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Symmetry

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Resonator
Analysis

Conclusions



Variation in Quality of Resonance

CAD for
MEMS

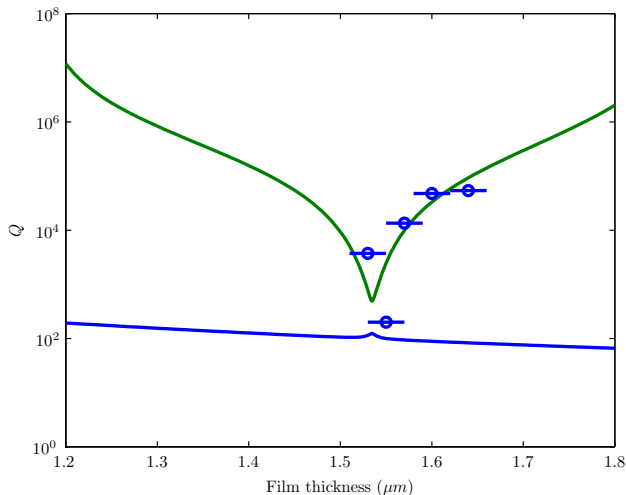
Resonant
MEMS

Anchor
Losses

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Symmetry

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Resonator
Analysis

Conclusions



Simulation and lab measurements vs. disk thickness

Explanation of Q Variation

CAD for
MEMS

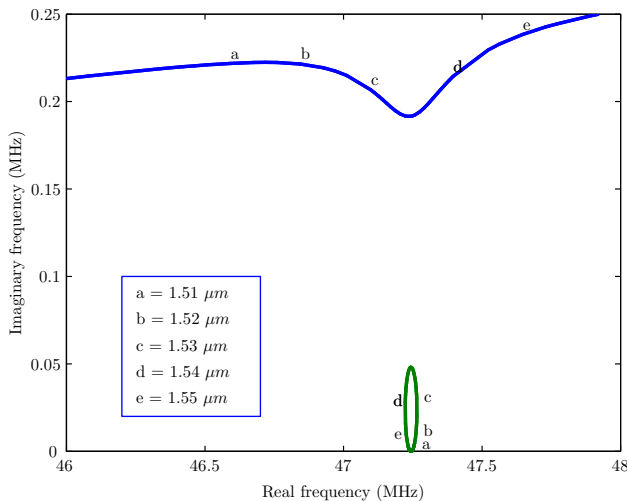
Resonant
MEMS

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Conclusions



Interaction of two nearby eigenmodes

Contributions

CAD for
MEMS

Resonant
MEMS

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Symmetry

Disk
Resonator
Analysis

Conclusions

- Built disk model in HiQLab and verified against lab measurements
- Demonstrated dominance of anchor loss for this device
- Predicted geometric sensitivity of quality factor Q (which was subsequently verified in the lab)
- Explained Q sensitivity in terms of mode interference

Contributions Summary (1)

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- Application modeling
 - Finite element models of several devices
 - Discovery of effects of mode interference
 - Importance of anchor loss vs thermoelastic damping
- Mathematical analysis
 - Reformulation of perfectly-matched layers
 - Analysis of discretization and parameter choice in PMLs
 - Complex symmetry-preserving model reduction
 - Perturbation solution for thermoelastic damping
- Software: HiQLab, FEAPMEX, SUGAR

Contributions Summary (2)

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- HiQLab (about 33000 lines of code)
 - Collaborations at Berkeley, Cornell, Stanford, Bosch
- FEAPMEX (about 5000 lines of code)
 - 2400+ page views
 - Used for instrument models, stochastic structural analysis, ultrasonic nondestructive evaluation problems, material parameter identification problems
- SUGAR (about 18000 lines of code)
 - 2000+ downloads
 - Used in classes at Berkeley, Cornell, Johns Hopkins
 - Continued research use for design optimization

Other Contributions

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- Lowered complexity of `roots` from $O(n^3)$ to $O(n^2)$
 - Code to go into next LAPACK release
- Developed first sparse subspace continuation code
 - Going into the next Matcont release
- Developed new network tomography method
- Designed initial security model for OceanStore
- Served as IEEE 754R secretary
- Responsible for last CLAPACK version

Future Work

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- Code development
 - Structural elements and elements for different physics
 - Design and implementation of parallelized version
- Theoretical analysis
 - More damping mechanisms
 - Sensitivity analysis and variational model reduction
- Application collaborations
 - Use of nonlinear effects (quasi-static and dynamic)
 - New designs (e.g. internal dielectric drives)
 - Continued experimental comparisons

Conclusions

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- RF MEMS are a great source of problems
 - Interesting applications
 - Interesting physics (and not altogether understood)
 - Interesting numerical mathematics

<http://www.cs.berkeley.edu/~dbindel>

Sources of Damping

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
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Resonator
Analysis

Conclusions

- Fluid damping
 - Air is a viscous fluid ($Re \ll 1$)
 - Can operate in a vacuum
 - Shown not to dominate in many RF designs
- Material losses
 - Low intrinsic losses in silicon, diamond, germanium
 - Terrible material losses in metals
- Thermoelastic damping
 - Volume changes induce temperature change
 - Diffusion of heat leads to mechanical loss
- Anchor loss
 - Elastic waves radiate from structure

Sources of Damping

CAD for
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Fabrication Outline

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



- 1 Si wafer
- 2 Deposit 2 microns SiO₂
- 3 Pattern and etch SiO₂ layer
- 4 Deposit 2 microns polycrystalline Si
- 5 Pattern and etch Si layer
- 6 Release etch remaining SiO₂

Fabrication Outline

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Fabrication Outline

CAD for
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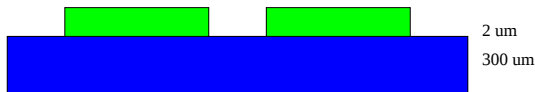
Resonant
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Fabrication Outline

CAD for
MEMS

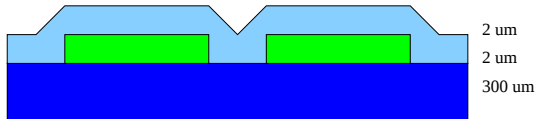
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Fabrication Outline

CAD for
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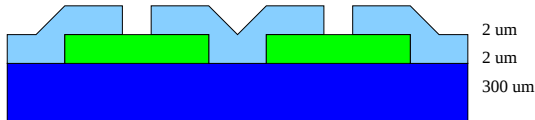
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Fabrication Outline

CAD for
MEMS

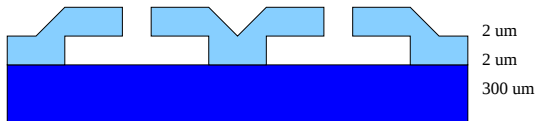
Resonant
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- 1 Si wafer
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Fabrication Result

CAD for
MEMS

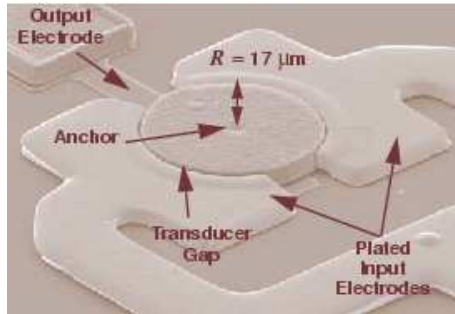
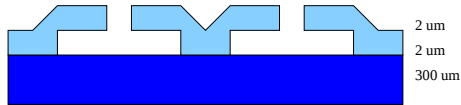
Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions



(C. Nguyen, iMEMS 02)

Role of simulation

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

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Symmetry

Disk
Resonator
Analysis

Conclusions

HiQLab: Modeling RF MEMS

- Explore fundamental device physics
 - Particularly details of damping
- Detailed finite element modeling
- Reduced models eventually to go into SUGAR

SUGAR: “Be SPICE to the MEMS world”

- Fast enough for early design stages
- Simple enough to attract users
- Support design, analysis, optimization, synthesis
- Verify models by comparison to measurement

Why simulate?

CAD for
MEMS

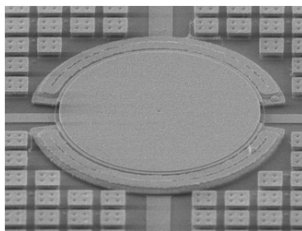
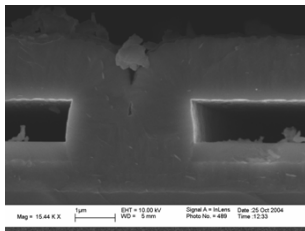
Resonant
MEMS

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Symmetry

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Resonator
Analysis

Conclusions



- “Build and break” is too expensive
 - Wafer processing costs months, thousands of dollars
 - Fabrication is imprecise
 - Days or weeks to take good measurements
- Good experiments need good hypotheses
- Even when device behavior is understood, still need to understand system behavior

From simulation to synthesis

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

Computer can assist at many levels:

- Fundamental physics
- Detailed device models
- System-level models and macromodels
- Metrology
- Design optimization
- Design synthesis

Research thrusts

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- Model development (e.g. new finite elements)
- Numerical algorithms (e.g. model reduction)
- Numerical software engineering (SUGAR, HiQLab)
- Metrology and comparison to measurement
- Optimization and design synthesis

Research group

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

Faculty		Students	
A. Agogino	(ME)	D. Bindel	(CS)
Z. Bai	(Math,CS,UCD)	J.V. Clark	(AS&T)
J. Demmel	(Math,CS)	C. Cobb	(ME)
S. Govindjee	(CEE)	D. Garmire	(CS)
R. Howe	(EE,ME)	T. Koyama	(CEE)
K.S.J. Pister	(EE)	J. Nie	(Math)
C. Sequin	(CS)	H. Wei	(CEE)
		Y. Zhang	(CEE)

SUGAR

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

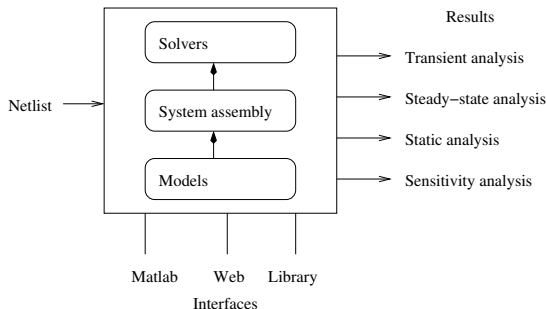
Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

Goal: “Be SPICE to the MEMS world”

- Fast enough for early design stages
- Simple enough to attract users
- Support design, analysis, optimization, synthesis
- Verify models by comparison to measurement



SUGAR: Analysis of a micromirror

CAD for
MEMS

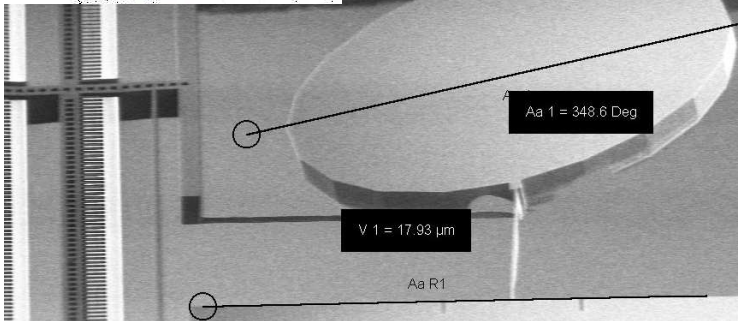
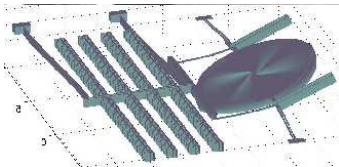
Resonant
MEMS

Anchor
Losses

Complex
Symmetry

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Resonator
Analysis

Conclusions



(Mirror design by M. Last)

SUGAR: Design synthesis

CAD for
MEMS

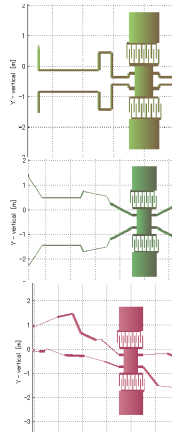
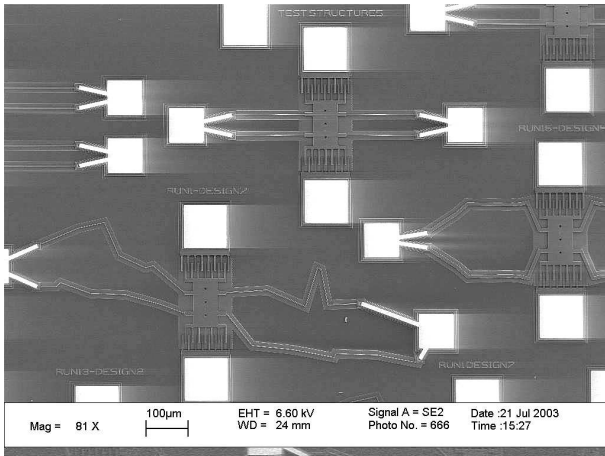
Resonant
MEMS

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Losses

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Analysis

Conclusions



SUGAR: Comparison to measurement

CAD for
MEMS

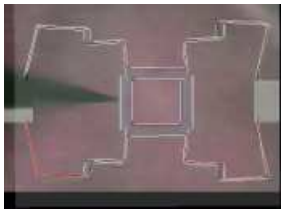
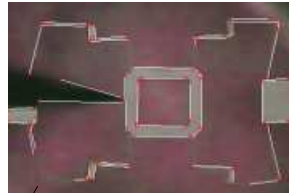
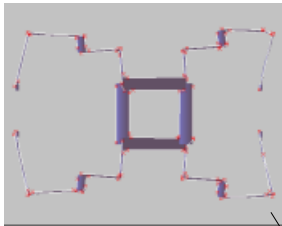
Resonant
MEMS

Anchor
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Analysis

Conclusions



Elastic PMLs

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

$$\int_{\Omega} \epsilon(w) : C : \epsilon(u) d\Omega - \omega^2 \int_{\Omega} \rho w \cdot u d\Omega = \int_{\Gamma} w \cdot t_n d\Gamma$$
$$\epsilon(u) = \left(\frac{\partial u}{\partial x} \right)^s$$

- Start from standard weak form
- Introduce transformed $\tilde{x}$ with $\frac{\partial \tilde{x}}{\partial x} = \Lambda$
- Map back to reference system ($J_{\Lambda} = \det(\Lambda)$)
- All terms are symmetric in w and u

Elastic PMLs

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

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Resonator
Analysis

Conclusions

$$\int_{\tilde{\Omega}} \tilde{\epsilon}(w) : C : \tilde{\epsilon}(u) d\tilde{\Omega} - \omega^2 \int_{\tilde{\Omega}} \rho w \cdot u d\tilde{\Omega} = \int_{\Gamma} w \cdot t_n d\Gamma$$
$$\tilde{\epsilon}(u) = \left(\frac{\partial u}{\partial \tilde{x}} \right)^s = \left(\frac{\partial u}{\partial x} \Lambda^{-1} \right)^s$$

- Start from standard weak form
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Elastic PMLs

CAD for
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Elastic PMLs

CAD for
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Continuum 2D model problem

CAD for
MEMS

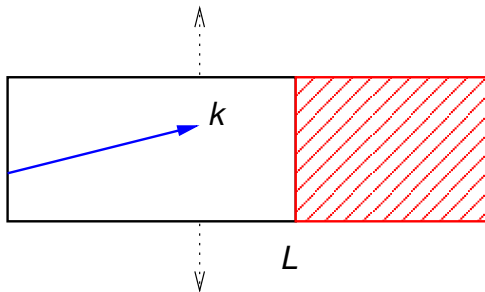
Resonant
MEMS

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Resonator
Analysis

Conclusions



$$\lambda(x) = \begin{cases} 1 - i\beta|x - L|^p, & x > L \\ 1 & x \leq L. \end{cases}$$

$$\frac{1}{\lambda} \frac{\partial}{\partial x} \left(\frac{1}{\lambda} \frac{\partial u}{\partial x} \right) + \frac{\partial^2 u}{\partial y^2} + k^2 u = 0$$

Continuum 2D model problem

CAD for
MEMS

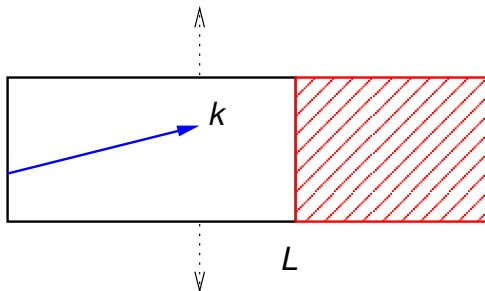
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$$\lambda(x) = \begin{cases} 1 - i\beta|x - L|^p, & x > L \\ 1 & x \leq L. \end{cases}$$

$$\frac{1}{\lambda} \frac{\partial}{\partial x} \left(\frac{1}{\lambda} \frac{\partial u}{\partial x} \right) - k_y^2 u + k^2 u = 0$$

Continuum 2D model problem

CAD for
MEMS

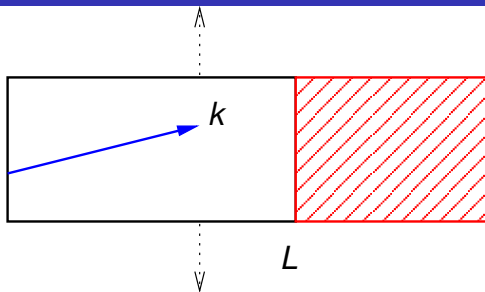
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$$\frac{1}{\lambda} \frac{\partial}{\partial x} \left(\frac{1}{\lambda} \frac{\partial u}{\partial x} \right) + k_x^2 u = 0$$

1D problem, reflection of $O(e^{-k_x \gamma})$

Discrete 2D model problem

CAD for
MEMS

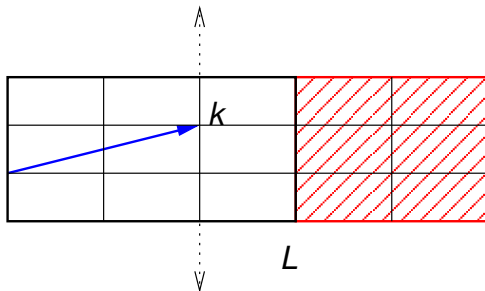
Resonant
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Symmetry

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Resonator
Analysis

Conclusions



- Discrete Fourier transform in y
- Solve numerically in x
- Project solution onto infinite space traveling modes
- Extension of Collino and Monk (1998)

Nondimensionalization

CAD for
MEMS

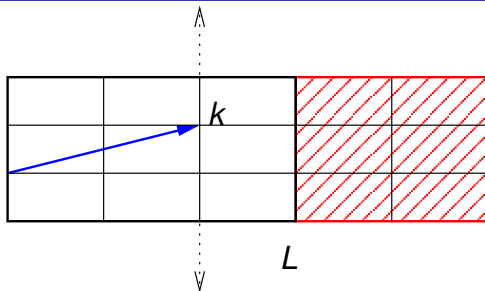
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Conclusions



$$\lambda(x) = \begin{cases} 1 - i\beta|x - L|^p, & x > L \\ 1 & x \leq L. \end{cases}$$

Rate of stretching:

$$\beta h^p$$

Elements per wave:

$$(k_x h)^{-1} \text{ and } (k_y h)^{-1}$$

Elements through the PML: N

Nondimensionalization

CAD for
MEMS

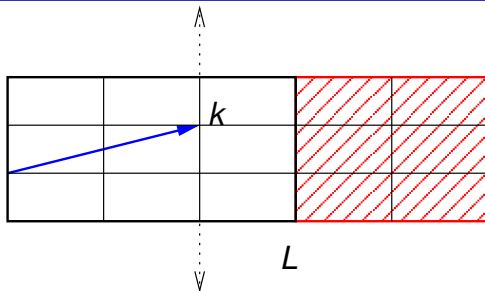
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Rate of stretching:

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$$(k_x h)^{-1} \text{ and } (k_y h)^{-1}$$

Elements through the PML: N

Discrete reflection behavior

CAD for
MEMS

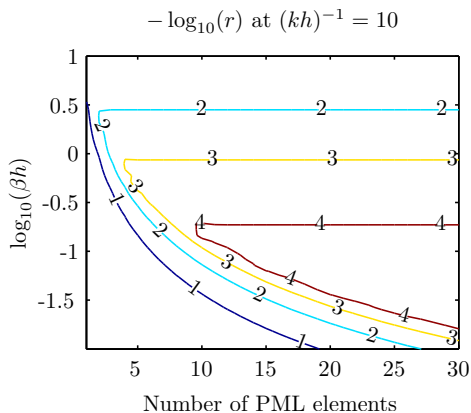
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Quadratic elements, $p = 1$, $(k_x h)^{-1} = 10$

Discrete reflection decomposition

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

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Symmetry

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Resonator
Analysis

Conclusions

Model discrete reflection as two parts:

- Far-end reflection (clamping reflection)
 - Approximated well by continuum calculation
 - Grows as $(k_x h)^{-1}$ grows
- Interface reflection
 - Discrete effect: mesh does not resolve decay
 - Does not depend on N
 - Grows as $(k_x h)^{-1}$ shrinks

Discrete reflection behavior

CAD for
MEMS

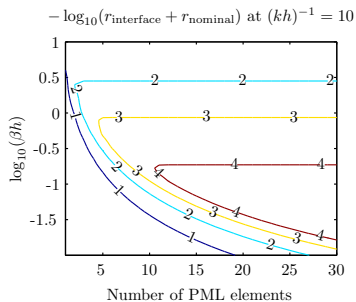
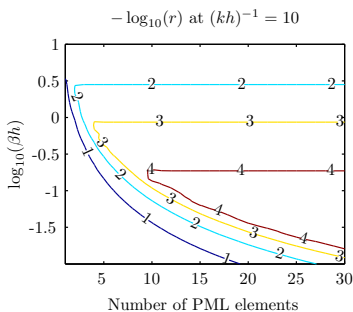
Resonant
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Conclusions



Quadratic elements, $p = 1$, $(k_x h)^{-1} = 10$

- Model does well at predicting actual reflection
- Similar picture for other wavelengths, element types, stretch functions

Choosing PML parameters

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

- Discrete reflection dominated by
 - Interface reflection when k_x large
 - Far-end reflection when k_x small
- Heuristic for PML parameter choice
 - Choose an acceptable reflection level
 - Choose β based on interface reflection at $k_x^{\max}$
 - Choose length based on far-end reflection at $k_x^{\min}$

Thermoelastic damping (TED)

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

u is displacement and $T = T_0 + \theta$ is temperature

$$\sigma = C\epsilon - \beta\theta\mathbf{1}$$

$$\rho u_{tt} = \nabla \cdot \sigma$$

$$\rho c_v \theta_t = \nabla \cdot (\kappa \nabla \theta) - \beta T_0 \text{tr}(\epsilon_t)$$

- Volumetric strain rate drives energy transfer from mechanical to thermal domain
 - Irreversible diffusion $\implies$ mechanical damping
 - Not often an important factor at the macro scale
 - Recognized source of damping in microresonators
- Zener: semi-analytical approximation for TED in beams
- We consider the fully coupled system

Nondimensionalization

CAD for
MEMS

Resonant
MEMS

Anchor
Losses

Complex
Symmetry

Disk
Resonator
Analysis

Conclusions

$$\sigma = \hat{C}\epsilon - \xi\theta\mathbf{1}$$

$$u_{tt} = \nabla \cdot \sigma$$

$$\theta_t = \eta \nabla^2 \theta - \text{tr}(\epsilon_t)$$

$$\xi := \left(\frac{\beta}{\rho c} \right)^2 \frac{T_0}{c_v} \text{ and } \eta := \frac{\kappa}{\rho c_v c L}$$

$$\text{Length} \sim L$$

$$\text{Time} \sim L/c, \text{ where } c = \sqrt{E/\rho}$$

$$\text{Temperature} \sim T_0 \frac{\beta}{\rho c_v}$$

Scaling analysis

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$$\sigma = \hat{C}\epsilon - \xi\theta \mathbf{1}$$

$$u_{tt} = \nabla \cdot \sigma$$

$$\theta_t = \eta \nabla^2 \theta - \text{tr}(\epsilon_t)$$

$$\xi := \left(\frac{\beta}{\rho c} \right)^2 \frac{T_0}{c_v} \text{ and } \eta := \frac{\kappa}{\rho c_v c L}$$

- Micron-scale poly-Si devices: ξ and η are $\sim 10^{-4}$.
- Small η leads to thermal boundary layers
- Linearize about $\xi = 0$

Discrete mode equations

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$$\sigma = \hat{C}\epsilon - \xi\theta 1$$

$$u_{tt} = \nabla \cdot \sigma$$

$$\theta_t = \eta \nabla^2 \theta - \text{tr}(\epsilon_t)$$

$$\sigma = \hat{C}\epsilon - \xi\theta 1$$

$$-\omega^2 u = \nabla \cdot \sigma$$

$$i\omega\theta = \eta \nabla^2 \theta - i\omega \text{tr}(\epsilon)$$

$$-\omega^2 M_{uu}u + K_{uu}u + K_{ut}\theta = 0$$

$$i\omega D_{tt}\theta + K_{tt}\theta + i\omega D_{tu}u = 0$$

Perturbation computation

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$$\begin{aligned}-\omega^2 M_{uu} u + K_{uu} u + K_{ut} \theta &= 0 \\ i\omega D_{tt} \theta + K_{tt} \theta + i\omega D_{tu} u &= 0\end{aligned}$$

Approximate ω by perturbation about $K_{ut} = 0$:

$$\begin{aligned}-\omega_0^2 M_{uu} u_0 + K_{uu} u_0 &= 0 \\ i\omega_0 D_{tt} \theta_0 + K_{tt} \theta_0 + i\omega_0 D_{tu} u_0 &= 0\end{aligned}$$

Choose $v : v^T u_0 \neq 0$ and compute

$$\begin{bmatrix} (-\omega_0^2 M_{uu} + K_{uu}) & -2\omega_0 M_{uu} u_0 \\ v^T & 0 \end{bmatrix} \begin{bmatrix} \delta u \\ \delta \omega \end{bmatrix} = \begin{bmatrix} -K_{ut} \theta_0 \\ 0 \end{bmatrix}$$

Comparison to Zener's model

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MEMS

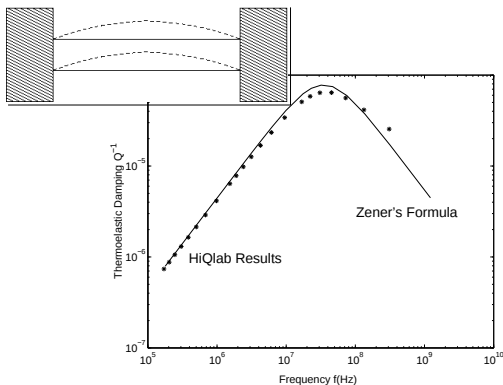
Resonant
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- Comparison of fully coupled simulation to Zener approximation over a range of frequencies
- Real and imaginary parts after first-order correction agree to about three digits with Arnoldi

Thermoelastic boundary layer

CAD for
MEMS

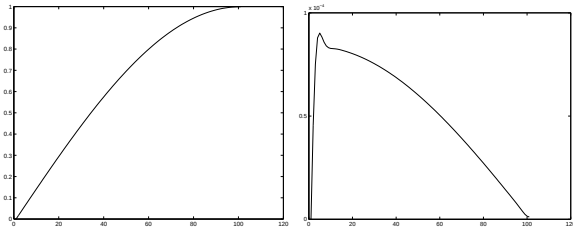
Resonant
MEMS

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Conclusions



- One-dimensional test problem (longitudinal mode in a bar)
- Fixed temperature and displacement at left
- Free at right

Shear ring resonator

CAD for
MEMS

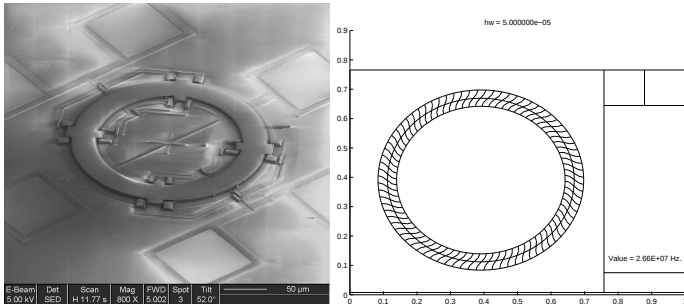
Resonant
MEMS

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Conclusions



- Ring is driven in a shearing motion
- Can couple ring to other resonators
- How do we track the desired mode?

Mode tracking

CAD for
MEMS

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Conclusions

Find a continuous solution to

$$\left(K(s) - \omega(s)^2 M(s) \right) u(s) = 0.$$

- K and M are symmetric and $M > 0$
- Eigenvectors are M -orthogonal
- Perturbation theory gives good shifts
- Look if $u(s+h)$ and $u(s)$ are on the same path by looking at $u(s+h)^T M(s+h) u(s)$
- Many more subtleties in the nonsymmetric case
 - Focus of the *CIS algorithm*

Mode tracking in a shear resonator

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